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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re Applicant:

Leonel R. Arana et al.

Serial No.:

10/807,836

Filed:

March 24, 2004

For:

Microfabricated Hot Wire

Vacuum Sensor

Art Unit:

nit: 2813

Examiner:

Heather Anne Doty

Docket:

TTL.1133US

P19113

Assignee:

Intel Corporation

Mail Stop AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## REPLY TO FINAL REJECTION

Sir:

In response to the final rejection mailed March 20, 2006, please amend the abovereferenced patent application as follows:

Date of Deposit. April 11, 2006

I hereby certify that this document is being facsimile transmitted to the United States Patenty and Trademark Office (Fax No. 571/273-9300) on the date Indicated above.

Cynthia L. Hayder